



Zeiss Supra 40VP Field Emission Scanning Electron Microscope

The Supra40VP FESEM allows surface examination down to nanometer scales in either High Vacuum or Variable Pressure (VP) mode. It has a Nanometer Pattern Generation System (NPGS) that provides a powerful, versatile, and easy to use system for electron beam lithography. Detectors available include: In-lens SE, Everhart-Thornley SE, and VPSE.